

METHOD AND APPARATUS FOR HIGH-SPEED INSPECTION AND REVIEW

Abstract of the Disclosure

5 One embodiment disclosed relates to an apparatus for substrate inspection and review. The apparatus includes at least a first subsystem, a processor, and a second subsystem. The first subsystem is used for inspecting said substrate. The processor is utilized for identifying regions of said substrate for review. The second subsystem is used for reviewing at least a portion of said
10 identified regions.